

Special Issue

Structured Optical Surfaces and Interfaces, Fabrication and Characterization

Message from the Guest Editor

It is my pleasure to invite your contributions to this Special Issue, seeking to collect research papers and review articles that focus on the following: (1) fabrication and, (2) characterization of optical structured surfaces and interfaces; including evolutionary, disruptive, revolutionary, and incremental techniques and methods.

- micro- and nano-structured optical surfaces
- bio-mimetic optical structures
- layered metamaterials
- surface hierarchical structures
- optical nano-surface fabrication
- plasmonic and photonic nanopillars
- nanorod arrays
- nanosphere optical layers
- lithographic nano/micro-fabrication
- optical surface modification
- subwavelength diffractive optics
- surface holograms
- nano-imprinting lithography
- optical surface characterization
- metamaterial absorbers
- functional optical surfaces

Guest Editor

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Deadline for manuscript submissions

closed (30 September 2021)



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About the Journal

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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